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LIST OF PRIOR ART CITED BY APPLICANT
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U.S. PATENT DOCUMENTS

| EXAMINER INITIAL | | DOCUMENT NUMBER | DATE | NAME | CLASS | SUBCLASS | FILING DATE IF APPROPRIATE |
|---------------------|----|-----------------|---------|---------------|-------|----------|-------------------------------|
| RP | AA | 4770895 | 9/1988 | Hartley | 427 | 10 | |
| | AB | 5091320 | 2/1992 | Aspner et al | 437 | F | |
| | AC | 5526117 | 6/1996 | Wielich et al | 356 | 369 | |
| | AD | 5582646 | 12/1996 | Woolgan et al | 118 | 708 | |
| | AE | 5929995 | 7/1999 | Johr | 356 | 369 | |
| | AF | 6573999 | 6/2003 | Yang | 356 | 632 | |
| RP | AG | 4934788 | 6/1990 | Southwell | 350 | 164 | |
| | AH | | | | | | |
| | AI | | | | | | |
| | AJ | | | | | | |
| | AK | | | | | | |

FOREIGN PATENT DOCUMENTS

| | | DOCUMENT NUMBER | DATE | COUNTRY | CLASS | SUBCLASS | TRANSLATION | |
|--|----|-----------------|------|---------|-------|----------|-------------|----|
| | AL | | | | | | YES | NO |
| | AM | | | | | | | |

OTHER PRIOR ART (Including Author, Title, Date, Pertinent Pages, Etc.)

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| | AR | | | | | | | |
| | AS | | | | | | | |

EXAMINER /Roy Punnoose/ DATE CONSIDERED 01/21/2007

EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

PLEASE USE THIS FOR PTO FORM 1449 REGARDING ARTICLES

RP

1. "Optical Characterization of Continuous Compositional Gradients in Thin Films by Real Time Spectroscopic Ellipsometry", S. Kim and R.W. Collins, Appl. Phys. Lett. 67 (1995), 3010.
2. "Growth of $\text{Al}_x\text{Ga}_{1-x}\text{As}$ Parabolic Quantum Wells by Real-Time Feedback Control of Composition", D.E. Aspnes, W.E. Quinn, M.C. Tamargo, M.A.A. Pudensi, S.A. Schwarz, M.J.S.P. Brasil, R.E. Nahory, and S. Gregory, Appl. Phys. Lett. 60 (1992), 2776.
3. "Real-time Control of the MBE Growth of InGaAs in InP", J.A. Roth, D.H. Chow, G.L. Olson, P.D. Brewer, W.S. Williamson, and B. Johs, J. Crystal Growth 201/202 (1999), 31.
4. "Status of HgCdTe-MBE Technology for Producing Dual-Band Infrared Detectors", R.D. Rajavel, P.D. Brewer, D.M. Jamba, J.E. Jensen, C. LeBeau, G.L. Olson, J.A. Roth, W.S. Williamson, J.W. Bangs, P. Goetz, J.L. Johnson, E.A. Patten, J.A. Wilson, J. Crystal Growth 214/215 (2000), 1100.
5. In Situ Multi-Wavelength Ellipsometric Control of Thickness and Composition for Bragg Reflection Structures", C. Herzinger, B. Johs, P. Chow, D. Reich, G. Carpenter, D. Croswell, and J. Van Hove, Mat. Res. Soc. Symp. Proc. Vol. 406 (1996), 347.
6. "Closed-loop Control of Resonating Tunneling Diode Barrier Thickness Using In Situ Spectroscopic Ellipsometry", J.A. Roth, W.S. Williamson, D.H. Chow, G.L. Olson, and B. Johs, J. Vac. Sci. Technol. B 18 (2000), 1439.
7. "In situ Spectral Ellipsometry for Real-Time Measurement and Control", W.M. Duncan and S.A. Henck, Appl. Surf. Sci. 63 (1993), 9.
8. "In Situ Ellipsometric Diagnosis of Multilayer Thin Film Deposition During Sputtering", X. Gao, D.W. Glenn, and J.A. Woollam, Thin Solid Films 313-314 (1998), 511. G.E. Jellison Jr., Thin Solid Films 234 (1993), 416. data, see references [9,10]).
9. "Spectroscopic Ellipsometry Data Analysis: Measurement Versus Calculated Quantities", G.E. Jellison Jr., Thin Solid Films 313-314 (1998), 511.
10. "Overview of Variable Angle Spectroscopic Ellipsometry (VASE), Part 1: Basic Theory and Typical Applications", J.A. Woollam, B. Johs, C.M. Herzinger, J. Hilfiker, R. Synowicki, and C. L. Bungay, SPIE Critical Reviews Vol. CR72 (1999), 3.
11. "Minimal-data Approaches for Determining Outer-layer

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Dielectric Responses of Films From Kinetic Reflectometric and Ellipsometric Measurements", D.E. Aspnes, J. Opt. Soc. Amer. A 10 (1993), 974.

12. "Optical Approaches to Determine Near-Surface Compositions During Epitaxy", D.E. Aspnes, J. Vac. Sci. Technol. A 14 (1996), 960. F.K. Urban III and M.F. Tabet, J. Vac. Sci. Technol. A 11 (1993), 976.

13. "Virtual Interface Method for In Situ Ellipsometry fo Films Grown on Unknown Substrates", F.K. Urban III and M.F. Tabet, J. Vac. Sci. Technol. A 11 (1993), 976.

14. "Real Time Monitoring of the Growth of Transparent Thin Films by Spectroscopic Ellipsometry", M. Kildemo and B. Drevillon, Rev. Sci. Instrum. Vol. 67, No. 5 (1996), 1957.

15. "Characterization of Quasi-Rugate Filters Using Ellipsometric Measurements", A.V. Tikhonravov, M.K. Trubetskov, J. Hrdina, and J. Sobota, Thin Solid Films 277 (1996), 83.

16. "Approximation of Reflection Coefficients for Rapid Real-time Calculation of Inhomogeneous Films", M. Kildemo, O. Hunderi, B. Drevillon, J. Opt. Soc. Am. A 14 (1997), 931.

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18. "Real Time Control of Plasma Deposited Optical Filters by Multiwavelength Ellipsometry", T. Heitz, A. Hofrichter, P. Bulkin, and B. Drevillon, J. Vac. Sci. Technol. A 18 (2000), 1303.

19. "Direct Numerical Inversion Method for kinetic Ellipsometry Data. 1. Presentation of the Method and Numerical Evaluation", D. Kouznetsov, A. Hofirchter, and B Drevillon, Appl. Opt. 41 (2002) 4510.

20. "Recherches Sur La Propagation Des Ondes Electromagnetiques Sinusoidales Dans Les Milieuc Stratifies Application Aux Couches Minces", F. Abeles, Ann. De Physique, 5 (1950) 596.

24. Model M2000X, J.A. Woollam Co., Inc., Lincoln, NE USA.

25. "Data Analysis for Spectroscopic Ellipsometry", G.E. Jellison Jr., Thin Solid Films, 234, 1993, 416-422.

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26. "In situ and Ex Situ Applications of Spectroscopic Ellipsometry", J. A. Woollam, B. Johs, W. McGahan, P. Snyder, J. Hale, H. Yao, Mat. Res. Soc. Proc., Vol 324, 1994, p. 15.